



Call for Papers

2020 Summer Topical Meeting

Advancing Precision in Additive Manufacturing

Oak Ridge National Laboratory
Manufacturing Demonstration Facility
Knoxville, Tennessee, USA
July 13-17, 2020

Topics

Dimensional accuracy and surface finish in additive manufacturing (AM)

- State of the art: What level of precision is achievable?
- · Functional specifications for form and finish
- · Prediction and modeling of dimensional errors and surface topography
- Developments in fabricating lattice structures with high integrity
- Diversity in scale of features: large-scale → micro-nano

Design for manufacturing

- Design rules and tolerancing for AM
- Topology optimization in the context of AM and achieving precision
- Novel designs for flexures and kinematic couplings
- · Metallurgy and fatigue issues in high-cycle precision applications

■ Characterizing the performance of AM machines

- In situ process monitoring, e.g. melt zone temperature, powder bed
- · In-process measurement of workpiece shape and topography
- Using artifacts to assess machine performance; round-robin testing
- Holistic views of the control system, process feedback, correction
- Machine learning to conquer the complex AM parameter space

Standards

- · Certifying AM equipment capabilities and material properties
- Industrial demands for ASTM & ISO standards

■ Integrating AM into a holistic manufacturing process

- Cost-benefit trade-offs of using AM within a complex process chain
- · Engineered partnerships between AM and secondary finishing
- · Kinematic tooling or pallets for repeatable part handling

Metrology

- Surface topography measurements on rough as-built surfaces
- Dimensional metrology of internal features using computed tomography
- Multi-sensor approaches, data fusion, and machine learning
- Complex form measurement, registration, and fitting of point clouds
- Measurement of 3D lattice strut dimensional accuracy and integrity
- · Characterization of internal defects and voids

Tutorials on July 13th & Tours on July 17th

Short abstracts due May 4, 2020 www.aspe.net

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